

Contents

Preface *XXIII*

1 The History of Vacuum Science and Vacuum Technology 1

References 16

Further Reading 17

2 Applications and Scope of Vacuum Technology 19

References 27

3 Gas Laws and Kinetic Theory of Gases 29

3.1 Description of the Gas State 29

3.1.1 State Variables 29

3.1.2 Extensive Quantities 33

3.1.3 Equation of State of an Ideal Gas 35

3.1.4 Mixtures of Different Gas Species 37

3.2 Kinetic Theory of Gases 38

3.2.1 Model Conceptions 38

3.2.2 Wall Pressure due to Impacting Particles 39

3.2.3 Maxwell–Boltzmann Velocity Distribution 41

3.2.4 Collision Rate and Effusion 44

3.2.5 Size of Gas Particles and Free Path 45

3.3 Transport Properties of Gases 50

3.3.1 Pressure Dependence 50

3.3.2 Transport of Frictional Forces in Gases and Viscosity 51

3.3.3 Transport of Heat in Gases and Thermal Conductivity 55

3.3.4 Diffusion 63

3.4 Real Gases 65

3.4.1 Equations of State 65

3.4.2 Particle Properties and Gas Behavior 69

3.5 Vapors 75

3.5.1 Saturation Vapor Pressure 75

3.5.2 Evaporation Rate 79

	References	81
	Comprehensive general treatments of the subject	82
4	Gas Flow	83
4.1	Types of Flows and Definitions	83
4.1.1	Characterizing Flow, Knudsen Number, and Reynolds Number	83
4.1.2	Gas Flow, Throughput, and Pumping Speed	87
4.1.3	Flow Resistance and Flow Conductance	90
4.1.4	Effective Pumping Speed of a Vacuum Pump	92
4.2	Inviscid Viscous Flow and Gas Dynamics	93
4.2.1	Conservation Laws	93
4.2.2	Gradual Change of Cross-Sectional Area: Isentropic Change of State	95
4.2.3	Critical Flow	98
4.2.4	Choked Flow at Low Outlet Pressure	100
4.2.5	Contraction of Flow into Aperture and Tube	101
4.2.6	Examples of Nozzle Flow	102
4.2.7	Straight and Oblique Compression Shocks	106
4.2.8	Laval Nozzle and Effluent Flow against Counterpressure	108
4.2.9	Flow Around a Corner (Prandtl–Meyer Flow)	111
4.3	Frictional–Viscous Flow through a Tube	114
4.3.1	Laminar and Turbulent Flows through a Tube	114
4.3.2	Airflow through a Tube	118
4.3.3	Air Inflow to a Vessel: Examples	120
4.3.4	Tube at the Inlet of a Pump: Examples	125
4.3.5	Flow through Ducts with Noncircular Cross Sections	128
4.3.6	Influence of Gas Species on Flow	130
4.4	Molecular Flow under High-Vacuum and Ultrahigh-Vacuum Conditions	131
4.4.1	Flow Pattern, Definitions, and Transmission Probability	131
4.4.2	Molecular Flow through an Aperture	135
4.4.3	Molecular Flow through a Tube with Constant Cross-Sectional Area	137
4.4.4	Molecular Flow through a Tube with Circular Cross Section	139
4.4.5	Molecular Flow through Tubes with Simple Cross-Sectional Geometry	140
4.4.6	Tube Bend and Tube Elbow	143
4.4.7	Series Connection of Tube and Aperture	145
4.4.8	Series Connection of Components	146
4.4.9	Molecular Flow through Conical Tube with Circular Cross Section (Funnel)	148
4.4.10	Component in the Inlet Line of a Pump	150
4.5	Flow throughout the Entire Pressure Range	151
4.5.1	Flow Ranges	151
4.5.2	Flow through a Thin Aperture with Circular Cross Section	151

- 4.5.3 Flow through a Long Tube with Circular Cross Section 154
- 4.6 Flow with Temperature Difference, Thermal Effusion, and Transpiration 158
- 4.7 Measuring Flow Conductances 162
 - 4.7.1 Necessity of Measurement 162
 - 4.7.2 Measurement of Intrinsic Conductances (Inherent Conductances) 162
 - 4.7.3 Calculation of Reduced Conductance (Assembly Conductance) 164
 - 4.7.4 Measuring Reduced Conductances 164
- References 166
- Further Reading 166

- 5 Analytical and Numerical Calculations of Rarefied Gas Flows 167**
 - 5.1 Main Concepts 167
 - 5.1.1 Knudsen Number and Gas Rarefaction 167
 - 5.1.2 Macroscopic Quantities 168
 - 5.1.3 Velocity Distribution Function 168
 - 5.1.4 Global Equilibrium 169
 - 5.1.5 Local Equilibrium 170
 - 5.1.6 Boltzmann Equation 170
 - 5.1.7 Transport Coefficients 172
 - 5.1.8 Model Equations 174
 - 5.1.9 Gas–Surface Interaction 175
 - 5.2 Methods of Calculations of Gas Flows 178
 - 5.2.1 General Remarks 178
 - 5.2.2 Deterministic Methods 178
 - 5.2.3 Probabilistic Methods 179
 - 5.3 Velocity Slip and Temperature Jump Phenomena 181
 - 5.3.1 Viscous Slip Coefficient 182
 - 5.3.2 Thermal Slip Coefficient 183
 - 5.3.3 Temperature Jump Coefficient 184
 - 5.4 Momentum and Heat Transfer Through Rarefied Gases 185
 - 5.4.1 Planar Couette Flow 186
 - 5.4.2 Cylindrical Couette Flow 189
 - 5.4.3 Heat Transfer between Two Plates 193
 - 5.4.4 Heat Transfer between Two Coaxial Cylinders 195
 - 5.5 Flows Through Long Pipes 199
 - 5.5.1 Definitions 199
 - 5.5.2 Free Molecular Regime 201
 - 5.5.3 Slip Flow Regime 202
 - 5.5.4 Transitional Regime 203
 - 5.5.5 Arbitrary Pressure and Temperature Drops 208
 - 5.5.6 Variable Cross Section 214
 - 5.5.7 Thermomolecular Pressure Ratio 216
 - 5.6 Flow Through an Orifice 218
 - 5.7 Modeling of Holweck Pump 221

- 5.8 Appendix A 223
 - 5.8.1 Tables 223
 - References 225

- 6 Sorption and Diffusion 229**
 - 6.1 Sorption Phenomena and the Consequences, Definitions, and Terminology 229
 - 6.2 Adsorption and Desorption Kinetics 234
 - 6.2.1 Adsorption Rate 234
 - 6.2.2 Desorption Rate 235
 - 6.2.3 Hobson Model of a Pump-down Curve 238
 - 6.2.4 Monolayer Adsorption Isotherms 242
 - 6.2.5 Multilayer Adsorption and Brunauer–Emmett–Teller (BET) Isotherm 244
 - 6.2.6 Monolayer Time 246
 - 6.3 Absorption, Diffusion, and Outgassing 247
 - 6.4 Permeation 254
 - References 256
 - Further Reading 256

- 7 Positive Displacement Pumps 259**
 - 7.1 Introduction and Overview 259
 - 7.2 Oscillating Positive Displacement Pumps 262
 - 7.2.1 Piston Pumps 262
 - 7.2.2 Diaphragm Pumps 264
 - 7.2.2.1 Design and Principle of Operation 264
 - 7.2.2.2 Pumping Speed and Ultimate Pressure 265
 - 7.2.2.3 Gas Ballast 266
 - 7.2.2.4 Drive Concepts 267
 - 7.2.2.5 Ultimate Pressure 267
 - 7.2.2.6 Influence of Gas Species on Pumping Speed and Ultimate Pressure 269
 - 7.2.2.7 Influence of Rotational Speed on Ultimate Pressure 269
 - 7.2.2.8 Design Principles 269
 - 7.2.2.9 Diaphragm Pumps in Chemical Laboratories 271
 - 7.2.2.10 Diaphragm Pumps as Backing Pumps to Turbomolecular Pumps 272
 - 7.2.2.11 Diaphragm Pumps Combined with Other Types of Vacuum Pumps 275
 - 7.3 Single-Shaft Rotating Positive Displacement Pumps 276
 - 7.3.1 Liquid Ring Vacuum Pumps 276
 - 7.3.1.1 Design and Principle of Operation 277
 - 7.3.1.2 Operating Properties and Dimensioning 278
 - 7.3.1.3 Designs 281
 - 7.3.1.4 Pump Units with Liquid Ring Vacuum Pumps 284
 - 7.3.1.5 Suggestions for Economical Operation 286
 - 7.3.2 Sliding Vane Rotary Pumps 287
 - 7.3.2.1 Operating Principle and Design 288

- 7.3.2.2 Dry-Running Sliding Vane Rotary Pumps 289
- 7.3.2.3 Oil-Lubricated Sliding Vane Rotary Pumps 290
- 7.3.2.4 Once-Through Lubricated Sliding Vane Rotary Pumps 292
- 7.3.2.5 Operating Behavior and Recommendations 293
- 7.3.2.6 Characteristic Curves and Ratings 295
- 7.3.3 Rotary Plunger Pumps 296
 - 7.3.3.1 Principle of Operation and Technical Design 296
 - 7.3.3.2 A Comparison of Sliding Vane Rotary Pumps and Rotary Plunger Pumps 300
- 7.3.4 Trochoidal Pumps 300
- 7.3.5 Scroll Pumps 302
 - 7.3.5.1 Principle of Compression 302
 - 7.3.5.2 Design 303
 - 7.3.5.3 Applications and Advantages 304
- 7.4 Twin-Spool Rotating Positive Displacement Pumps 305
 - 7.4.1 Screw-Type Pumps 305
 - 7.4.1.1 Operating Principle and Technical Design 305
 - 7.4.1.2 Heat Behavior and Technical Notes 311
 - 7.4.2 Claw Pumps 313
 - 7.4.2.1 Compression Principle 314
 - 7.4.2.2 Comparison with Roots Pumps 317
 - 7.4.2.3 Multistage Claw Pumps and Pump Combinations 317
 - 7.4.2.4 Speed Control 318
 - 7.4.2.5 Fields of Application 319
 - 7.4.3 Roots Pumps 319
 - 7.4.3.1 Principle of Operation 319
 - 7.4.3.2 Technical Setup 320
 - 7.4.3.3 Theoretical Basics 322
 - 7.4.3.4 Effective Gas Flow 322
 - 7.4.3.5 Compression Ratio K_0 at Zero Delivery 323
 - 7.4.3.6 Effective Compression Ratio and Volumetric Efficiency 324
 - 7.4.3.7 Gradation of Pumping Speed between Fore Pump and Roots Pump 325
 - 7.4.3.8 Pumping Speed and Ultimate Pressure 329
 - 7.4.3.9 Installation and Operating Suggestions 331
- 7.5 Specific Properties of Oil-Sealed Positive Displacement Pumps 331
 - 7.5.1 Pumping Speed and Producibile Ultimate Pressure 331
 - 7.5.1.1 Pumping Speed and Ultimate Partial Pressure 332
 - 7.5.1.2 Ultimate Pressure and Oil Selection 332
 - 7.5.2 Oil Backflow 336
- 7.6 Basics of Positive Displacement Pumps 337
 - 7.6.1 Pumping Down Vapors – Gas Ballast 337
 - 7.6.2 Power Requirements 342
 - 7.6.2.1 Isothermal Compression 343
 - 7.6.2.2 Adiabatic Compression 343

- 7.6.2.3 Polytropic Compression 343
- 7.6.2.4 Compression Power 344
- 7.7 Operating and Safety Recommendations 345
 - 7.7.1 Installation 345
 - 7.7.2 Starting and Shut Down, Inlet Valves 346
 - 7.7.3 Pump Selection and Operating Recommendations 347
 - 7.7.4 Technical Safety Recommendations 348
- 7.8 Specific Accessories for Positive Displacement Pumps 350
 - 7.8.1 Sorption Traps 350
 - 7.8.2 Safety Valves 351
 - 7.8.3 Oil Filter and Oil Cleaning 352
 - 7.8.4 Exhaust Filter (Oil–Mist Separator) 353
 - 7.8.5 Dust Filters 355
- References 356
- Further Reading on Positive Displacement Pumps 359

- 8 Condensers 361**
 - 8.1 Condensation Processes Under Vacuum 361
 - 8.1.1 Fundamentals 361
 - 8.1.2 Condensation of Pure Vapors 363
 - 8.1.3 Condensation of Gas–Vapor Mixtures 366
 - 8.1.4 Coolants 369
 - 8.2 Condenser Designs 370
 - 8.2.1 Surface Condensers for Liquid Condensation 370
 - 8.2.2 Direct Contact Condensers 372
 - 8.2.3 Condensate Discharge 374
 - 8.2.4 Surface Condensers for Solid Condensation 375
 - 8.3 Integrating Condensers into Vacuum Systems 376
 - 8.3.1 Condensers Combined with Vacuum Pumps 376
 - 8.3.2 Control 379
 - 8.4 Calculation Examples 380
- References 382

- 9 Jet and Diffusion Pumps 383**
 - 9.1 Introduction and Overview 383
 - 9.2 Liquid Jet Vacuum Pumps 385
 - 9.3 Steam Jet Vacuum Pumps 387
 - 9.3.1 Design and Function 387
 - 9.3.2 Performance Data, Operating Behavior, and Control 389
 - 9.3.3 Multistage Steam Jet Vacuum Pumps 393
 - 9.3.4 Organic Vapors as Driving Pump Fluids 395
 - 9.4 Diffusion Pumps 396
 - 9.4.1 Design and Principle of Operation 396

- 9.4.2 Pump Fluids 400
- 9.4.3 Baffles and Vapor Traps 401
- 9.4.4 Fractionating and Degassing 403
- 9.4.5 Operating Suggestions 404
- 9.4.6 Pumping Speed, Critical Backing Pressure, Hybrid Pumps 405
- 9.4.7 Calculating Performance Characteristics of Diffusion and Vapor Jet Pumps by Using a Simple Pump Model 407
- 9.5 Diffusion Pumps Versus Vapor Jet Pumps 415
 - References 417

- 10 Molecular and Turbomolecular Pumps 419**
 - 10.1 Introduction 419
 - 10.2 Molecular Pumps 421
 - 10.2.1 Gaede Pump Stage 422
 - 10.2.2 Holweck Pump Stage 426
 - 10.2.3 Siegbahn Pump Stage 427
 - 10.3 Molecular and Regenerative Drag Pump Combination 427
 - 10.3.1 Regenerative Pump Mechanism 428
 - 10.3.2 Pump Design and Applications 429
 - 10.4 Physical Fundamentals of Turbomolecular Pump Stages 430
 - 10.4.1 Pumping Mechanism 430
 - 10.4.2 Pumping Speed and Compression Ratio 431
 - 10.4.3 Gaede and Statistical Theory of the Pumping Effect 432
 - 10.4.3.1 Consideration with Gaede 432
 - 10.4.3.2 Statistical Consideration 434
 - 10.4.4 Thermal Balance 436
 - 10.5 Turbomolecular Pumps 439
 - 10.5.1 Design and Function 439
 - 10.5.2 Rotors of Turbomolecular Pumps 441
 - 10.5.2.1 Rotor Design 441
 - 10.5.2.2 Rotor Materials and Mechanical Requirements 442
 - 10.5.3 Safety Requirements 442
 - 10.5.4 Bearing Arrangements for Rotors in Turbomolecular Pumps 443
 - 10.5.4.1 Shaft with Two Ball Bearings 444
 - 10.5.4.2 Shaft With Permanent Magnet Bearing and Ball Bearing 445
 - 10.5.4.3 Magnetic Bearings 445
 - 10.5.5 Drives and Handling 447
 - 10.5.6 Heating and Cooling 448
 - 10.5.7 Special Designs 448
 - 10.6 Performance Characteristics of Turbomolecular Pumps 450
 - 10.6.1 Pumping Speed 450
 - 10.6.2 Compression Ratio, Ultimate Pressure, and Base Pressure 451
 - 10.6.3 Pump-down Times for Vacuum Chambers 452
 - 10.6.4 Pumping of High Gas Throughputs 453

10.7	Operation and Maintenance of Turbomolecular Pumps	455
10.7.1	Backing Pump Selection	455
10.7.2	General Notes	455
10.7.3	Startup	455
10.7.4	Obtaining Base Pressure	456
10.7.5	Operation in Magnetic Fields	456
10.7.6	Venting	456
10.7.7	Maintenance	457
10.8	Applications	457
	References	460
11	Sorption Pumps	463
11.1	Introduction	463
11.2	Adsorption Pumps	464
11.2.1	Working Principle	464
11.2.2	Design	466
11.2.3	Ultimate Vacuum and Pumping Speed	468
11.2.3.1	Ultimate Pressure with a Single Adsorption Pump	468
11.2.3.2	Ultimate Pressure with Two or More Adsorption Pumps	469
11.2.4	Operating Suggestions	471
11.3	Getter	472
11.3.1	Mode of Operation and Getter Types	472
11.3.2	NEG Pumps	474
11.3.2.1	Fundamentals of Bulk Getters/NEG	474
11.3.2.2	Design of NEG Pumps	478
11.3.2.3	Pumping Speed and Getter Capacity	479
11.3.2.4	Applications of NEG Pumps	481
11.3.2.5	Safety and Operating Recommendations	481
11.3.3	Evaporation/Sublimation Pumps	483
11.3.3.1	Evaporation Materials	483
11.3.3.2	Pumping Speed	484
11.3.3.3	Getter Capacity	486
11.3.3.4	Design of Evaporation Getters	487
11.4	Ion Getter Pumps	493
11.4.1	Working Principle	493
11.4.2	Technical Design (Diode Type)	497
11.4.3	Pumping Speed	498
11.4.4	The Differential Ion Pump	500
11.4.5	Triode Pumps	501
11.4.6	Distributed Ion Pumps	504
11.4.7	Residual Gas Spectrum	504
11.4.8	Operation	505
11.5	Orbitron Pumps	507
	References	508
	Further Reading	509

12	Cryotechnology and Cryopumps	511
12.1	Introduction	511
12.2	Methods of Refrigeration	512
12.2.1	Gas Refrigeration Processes	513
12.2.1.1	Stirling Process	515
12.2.1.2	Gifford–McMahon Process	516
12.2.1.3	Pulse Tube Process	518
12.2.2	Cryostat with Liquid Cryogen	519
12.2.3	Measurement of Low Temperatures	520
12.3	Working Principles of Cryopumps	520
12.3.1	Gas Condensation	523
12.3.2	Cryosorption	525
12.3.2.1	Solid Adsorbents	526
12.3.2.2	Cryotrapping	530
12.4	Design of Cryopumps	531
12.4.1	Cryotechnological Constructive Parameters	531
12.4.1.1	Thermal Radiation	531
12.4.1.2	Thermal Conduction	535
12.4.2	Vacuum Technology: Design Parameters	538
12.4.3	Construction Principles	541
12.4.3.1	Bath Cryopumps	541
12.4.3.2	Refrigerator Cryopumps	543
12.5	Characteristics of a Cryopump	547
12.5.1	Starting Pressure	547
12.5.2	Ultimate Pressure	548
12.5.3	Pumping Speed	549
12.5.4	Service Life	550
12.5.5	Capacity (Maximum Gas Intake)	552
12.5.6	Crossover Value	552
12.5.7	Maximum Tolerable pV Flow	552
12.5.8	Resistance to Thermal Radiation	552
12.5.9	Regeneration	552
12.5.10	Performance Comparison	555
12.6	Application Examples	555
12.6.1	Cryopumps with Forced Cooling Using Supercritical Helium	556
12.6.2	Combined Refrigerator/Liquid Cryopumps	558
12.6.3	Cryopumps with Forced Cooling Using Liquid Cryogen	559
12.6.4	Cryopumps in Large Research Applications	560
12.6.5	Cryopumps in Industrial Facilities	561
12.6.6	Development Trends for Cryopumps	561
	References	562
13	Total Pressure Vacuum Gauges	565
13.1	Introduction	565
13.2	Mechanical Vacuum Gauges	566

- 13.2.1 Principle and Classification 566
- 13.2.2 Corrugated-Diaphragm Vacuum Gauges 567
- 13.2.3 Capsule Element Vacuum Gauges (Measuring Range 1–100 kPa) 568
- 13.2.4 Bourdon Tube Vacuum Gauges (Measuring Range 1–100 kPa) 569
 - 13.2.4.1 Quartz Bourdon Tube Vacuum Gauges 570
- 13.2.5 Diaphragm (Membrane) Vacuum Gauges 571
 - 13.2.5.1 Diaphragm (Membrane) Vacuum Gauges with Mechanical Displays (Measuring Range 0.1–100 kPa) 571
 - 13.2.5.2 Diaphragm (Membrane) Vacuum Gauges with Electrical Converters 572
 - 13.2.5.3 Diaphragm (Membrane) Vacuum Gauges Using the Piezoresistive Principle 574
 - 13.2.5.4 Piezoelectric Vacuum Gauges 575
 - 13.2.5.5 Resonant Diaphragm Vacuum Gauges 575
 - 13.2.5.6 Capacitance Diaphragm Vacuum Gauges 576
 - 13.2.5.7 Thermal Transpiration 580
- 13.2.6 Pressure Switches and Pressure Controllers 582
- 13.3 Spinning Rotor Gauges (Gas-Friction Vacuum Gauges) 584
 - 13.3.1 Measuring Setup and Measuring Principle 584
 - 13.3.2 Retarding Effect due to Gas Friction 586
 - 13.3.3 Measuring Procedure 590
 - 13.3.4 Extending the Measuring Range toward Higher Pressures 592
 - 13.3.5 Measuring Uncertainty 592
- 13.4 Direct Electric Pressure Measuring Transducers 593
- 13.5 Thermal Conductivity Vacuum Gauges 594
 - 13.5.1 Principle 594
 - 13.5.2 Thermal Conductivity Vacuum Gauges with Constant Wire Temperature 597
 - 13.5.3 Thermal Conductivity Vacuum Gauges with Constant Heating 601
 - 13.5.4 Thermocouple Vacuum Gauges 602
 - 13.5.5 Thermistors 603
 - 13.5.6 Guidelines for Operating Thermal Conductivity Vacuum Gauges 603
- 13.6 Thermal Mass Flowmeters 604
- 13.7 Ionization Gauges 607
 - 13.7.1 Principle and Classification 607
 - 13.7.2 History of Ionization Gauges 608
 - 13.7.3 Emitting-Cathode Ionization Gauges (Hot-Cathode Ionization Gauges) 610
 - 13.7.3.1 Measurement Principle 610
 - 13.7.3.2 Design of Emitting-Cathode Ionization Gauges (Hot-Cathode Ionization Gauges) 613
 - 13.7.3.3 Concentric Triode 614
 - 13.7.3.4 Fine-Vacuum Ionization Gauges 614
 - 13.7.3.5 Bayard–Alpert Ionization Gauges 615
 - 13.7.3.6 Extractor Ionization Gauges 620

13.7.3.7	Additional Types of Emitting-Cathode Ionization Gauges	623
13.7.3.8	Operating Suggestions for Emitting-Cathode Ionization Gauges	623
13.7.4	Crossed-Field Ionization Gauges	625
13.7.4.1	Penning Gauges	625
13.7.4.2	Magnetron and Inverted Magnetron	630
13.7.5	Comparison of Both Types of Ionization Gauges	631
13.7.6	General Suggestions	633
13.8	Combined Vacuum Gauges	637
	References	639
14	Partial Pressure Vacuum Gauges and Leak Detectors	643
14.1	Introduction	643
14.2	Partial Pressure Analysis by Mass Spectrometry	643
14.2.1	Ion Source Design	648
14.2.1.1	Open Ion Sources (OIS)	649
14.2.1.2	Closed Ion Sources (CIS)	651
14.2.1.3	Molecular Beam Ion Sources (MBIS)	652
14.2.2	Filament Materials	652
14.2.3	Artifacts in the Mass Spectrum due to the Ion Source	654
14.2.4	Mass Analyzers	655
14.2.4.1	Quadrupole Mass Analyzers	655
14.2.4.2	Miniaturized Quadrupole Mass Analyzers	659
14.2.4.3	Magnetic Sector Analyzers	661
14.2.4.4	Autoresonant Ion Trap Mass Analyzers	664
14.2.5	Ion Detectors	665
14.2.5.1	Faraday Cups	665
14.2.5.2	SEM Detection	666
14.2.5.3	Discrete Dynode Electron Multipliers	667
14.2.5.4	Continuous Dynode Electron Multipliers (CDEM)	668
14.2.5.5	Microchannel Plate Detectors	669
14.2.6	Software for Mass Spectrometer Control	670
14.2.6.1	Analog Scan, Ion Current versus Mass	670
14.2.6.2	Selected Peaks, Ion Current versus Time	671
14.2.6.3	Leak Detection Mode	671
14.2.7	Further Applications of Mass Spectrometers	671
14.3	Partial Pressure Measurement Using Optical Methods	672
14.4	Leak Detectors	675
14.4.1	Basic Principles and Historical Overview	675
14.4.2	Helium Leak Detectors	675
14.4.2.1	Requirements and General Functions of Vacuum Leak Detection	675
14.4.2.2	Helium Sector Field Mass Spectrometers	676
14.4.2.3	Inlet Pressure of Helium Leak Detectors	677
14.4.2.4	Time Response of Helium Leak Detectors	678
14.4.2.5	Operating Principles of Helium Leak Detectors	679
14.4.2.6	Sniffing Devices for Helium Leak Detectors	683

14.4.2.7	Applications of Mass Spectrometer Helium Leak Detectors	684
14.4.3	Refrigerant Leak Detectors	685
14.4.3.1	Design and Operating Principle	685
14.4.3.2	Applications	687
14.4.4	Reference Leaks	687
14.4.4.1	Permeation Leaks	687
14.4.4.2	Conductance Leaks	688
14.4.4.3	Practical Realization of Reference Leaks	688
14.4.4.4	Calibrating Reference Leaks	689
14.4.5	Measuring Characteristics and Calibration of Leak Detectors	689
14.4.5.1	Leak Detectors as Test Equipment According to ISO 9001	689
14.4.5.2	Calibration Uncertainty	690
14.4.6	Leak Detectors Based on Other Sensor Principles	691
14.4.6.1	Helium Sniffers with Quartz Glass Membrane	691
14.4.6.2	Halogen Leak Detectors with Alkali Ion Sensors	691
14.4.6.3	Halogen Leak Detectors with Infrared Sensors	692
	References	692
15	Calibrations and Standards	697
15.1	Introduction	697
15.2	Calibration of Vacuum Gauges	700
15.2.1	Primary Standards	700
15.2.1.1	Liquid Manometers	701
15.2.1.2	Compression Manometer after McLeod	704
15.2.1.3	Piston Gauges and Pressure Balances	707
15.2.1.4	Static Expansion Method	710
15.2.1.5	Continuous Expansion Method	716
15.2.1.6	Other Primary Standards	722
15.2.2	Calibration by Comparison	723
15.2.3	Capacitance Diaphragm Gauges	724
15.2.4	Spinning Rotor Gauges	728
15.2.5	Ionization Gauges	731
15.3	Calibrations of Residual Gas Analyzers	733
15.4	Calibration of Test Leaks	735
15.5	Standards for Determining Characteristics of Vacuum Pumps	738
	References	742
16	Materials	747
16.1	Requirements and Overview of Materials	747
16.2	Materials for Vacuum Technology	749
16.2.1	Metals	749
16.2.1.1	The Most Important Metals and Metal Alloys	749
16.2.2	Technical Glass	753

16.2.2.1	Basics	753
16.2.2.2	Properties of Important Glasses	755
16.2.3	Ceramic Materials	757
16.2.3.1	Basics	757
16.2.3.2	Properties of Important Ceramics	757
16.2.3.3	Ceramics in Vacuum Technology	758
16.2.3.4	Ceramic/Metal Joining Technologies	758
16.2.3.5	Zeolite	758
16.2.4	Plastics	760
16.2.4.1	Basics	760
16.2.4.2	Properties of Major Plastics	760
16.2.5	Vacuum Greases	760
16.2.6	Oils	762
16.2.7	Coolants	763
16.3	Gas Permeability and Gas Emissions of Materials	763
16.3.1	Fundamentals	763
16.3.2	Gas Permeability	763
16.3.2.1	Gas Permeability of Metals	764
16.3.2.2	Gas Permeability of Glasses and Ceramics	764
16.3.2.3	Gas Permeability of Plastics	767
16.3.3	Gas Emissions	768
16.3.3.1	Basics	768
16.3.3.2	Saturation Vapor Pressure	768
16.3.3.3	Surface Desorption, Gas Diffusion from Bulk Material, Reference Values for Gas Emissions	770
16.3.4	Gas Diffusion from Bulk Material	770
16.3.5	Reference Values for Total Gas Emission Rates References Further Reading	774 774 775
17	Vacuum Components, Seals, and Joints	777
17.1	Introduction	777
17.2	Vacuum Hygiene	778
17.3	Joining Technologies in Vacuum Technology	781
17.3.1	Permanent Connections	783
17.3.1.1	Welding	784
17.3.1.2	Brazing	786
17.3.1.3	Adhesive Bonding	791
17.3.2	Detachable Connections	793
17.3.2.1	Elastomer-Sealed, Static, Detachable Connections (KF, ISO, and Others)	794
17.3.2.2	Metal-Sealed, Static, Detachable Connections	802
17.4	Components	806
17.4.1	Standard Components and Chambers	806
17.4.2	Mechanical Feedthroughs	813

17.4.3	Valves	817
17.4.4	Electrical Feedthroughs	823
17.4.5	Optical Feedthroughs	829
17.4.6	Heat Supply and Dissipation	833
	Abbreviations	839
	References	840
18	Operating Vacuum Systems	843
18.1	Electronic Integration of Vacuum Systems	843
18.1.1	Control by Means of Process Sensors and Automated Data Processing	843
18.1.1.1	Requirements and Applications	843
18.1.2	Integrated Solutions	845
18.1.2.1	ASCII Protocols	846
18.1.2.2	Standardized Bus Systems	846
18.1.2.3	Sensor Integration According to SECS and HSMS Standards	847
18.1.2.4	Process-Data Analysis	849
18.2	Calculation of Vacuum Systems	851
18.2.1	Analytical and Numerical Calculation	851
18.2.2	Calculation by Analog Electrical Network	852
18.2.3	Ultimate and Working Pressure in Vacuum Systems	854
18.2.3.1	Ultimate Pressure	854
18.2.3.2	Operating Pressure	855
18.3	Pressure Control	859
18.4	Techniques for Operating Low-Vacuum Systems	860
18.4.1	Overview	860
18.4.2	Assembly of Low-Vacuum Systems	861
18.4.3	Pumps: Types and Pumping Speeds	862
18.4.4	Low-Vacuum Pump Stands	862
18.4.5	Low-Vacuum Pressure Measurement	864
18.4.6	Pressure and Pump-Down Times in Low Vacuum	864
18.4.7	Venting	869
18.5	Techniques for Operating Fine-Vacuum Systems	870
18.5.1	Overview	870
18.5.2	Assembly of Fine-Vacuum Systems	870
18.5.3	Pumps: Types and Pumping Speeds	871
18.5.4	Pressure Measurement	871
18.5.5	Pump-Down Time and Ultimate Pressure	872
18.5.6	Venting	877
18.5.7	Fine-vacuum Pump Stands	877
18.6	Techniques for Operating High-Vacuum Systems	879
18.6.1	Pumps: Types and Pumping Speeds	879

- 18.6.2 Cleaning of Vacuum Gauges 880
- 18.6.3 High-Vacuum Pump Stands 882
 - 18.6.3.1 High-Vacuum Pump Stands with Diffusion Pumps 882
 - 18.6.3.2 High-Vacuum Pump Stands with Turbomolecular Pumps 889
 - 18.6.3.3 Fully Automatic High-Vacuum Pump Stands 890
- 18.6.4 Pump-Down Time and Venting 891
- 18.7 Techniques for Operating Ultrahigh-Vacuum Systems 892
 - 18.7.1 Overview 892
 - 18.7.2 Operating Guidelines for UHV Pumps 893
 - 18.7.2.1 Adsorption Pumps 894
 - 18.7.2.2 Ion Getter Pumps 894
 - 18.7.2.3 Titanium Evaporation Pumps 895
 - 18.7.2.4 Turbomolecular Pumps 896
 - 18.7.2.5 Cryopumps 896
 - 18.7.2.6 Bulk Getter (NEG) Pumps 896
 - 18.7.3 Pressure Measurement 897
 - 18.7.4 Pump-Down Times, Ultimate Pressure, and Evacuating Procedures 897
 - 18.7.5 Venting 898
 - 18.7.6 Ultrahigh-Vacuum Systems 898
 - 18.7.7 Ultrahigh-Vacuum (UHV) Components 898
 - 18.7.8 Ultrahigh-Vacuum (UHV) Pump Stands 899
 - 18.7.8.1 Large Ultrahigh-Vacuum (UHV) Facilities 901
 - References 904
- 19 Methods of Leak Detection 907**
 - 19.1 Overview 907
 - 19.1.1 Vacuum Leak Detection 907
 - 19.1.2 Overpressure Leak Detection 908
 - 19.1.3 Tracer-Gas Distribution in the Atmosphere in Front of a Leak 909
 - 19.1.4 Measurement Results with the Sniffing Method 910
 - 19.1.5 Tracer-Gas Species 911
 - 19.1.5.1 Helium 911
 - 19.1.5.2 Noble Gases Other Than Helium 911
 - 19.1.5.3 Hydrogen H₂ 911
 - 19.1.5.4 Methane CH₄ 912
 - 19.1.5.5 Carbon Dioxide CO₂ 912
 - 19.1.5.6 Sulfur Hexafluoride SF₆ 912
 - 19.2 Properties of Leaks 912
 - 19.2.1 Leak Rate, Units 912
 - 19.2.2 Types of Leaks 913

- 19.2.2.1 Properties of Pore-like Leaks 914
- 19.2.2.2 Permeation Leaks 916
- 19.2.2.3 Virtual Leaks in Vacuum Vessels 917
- 19.2.2.4 Liquid Leaks 917
- 19.3 Overview of Leak-Detection Methods
(See Also DIN EN 1779) 918
 - 19.3.1 General Guidelines for Tightness Testing 918
 - 19.3.2 Methods without Tracer Gas (Pressure Testing) 919
 - 19.3.2.1 Introduction 919
 - 19.3.2.2 Pressure Loss Measurement 920
 - 19.3.2.3 Pressure Rise Measurement 920
 - 19.3.2.4 Additional Methods 922
 - 19.3.3 Tracer-Gas Methods without Helium 922
 - 19.3.3.1 Basics 922
 - 19.3.3.2 Vacuum Leak Detection with Non-helium Tracer Gas 923
 - 19.3.3.3 Overpressure Leak Detection with Tracer Gases Other Than Helium 924
- 19.4 Leak Detection Using Helium Leak Detectors 925
 - 19.4.1 Properties of Helium Leak Detectors 925
 - 19.4.2 Testing of Components 926
 - 19.4.2.1 Testing Procedure, Integral Testing 926
 - 19.4.2.2 Procedure for Leak Localization 927
 - 19.4.3 Testing of Vacuum Systems 929
 - 19.4.3.1 General Considerations for Partial Flow Operation 930
 - 19.4.3.2 Points on Systems for Connecting Leak Detectors 931
 - 19.4.3.3 Detection Limit and Response Time 933
 - 19.4.4 Overpressure (Sniffing) Leak Detection with a Helium Leak Detector 934
 - 19.4.4.1 Integral Procedure (Total or Partial) 935
 - 19.4.4.2 Leak Localization with a Sniffer 936
- 19.5 Leak Detection with Other Tracer Gases 936
 - 19.5.1 Basics 936
 - 19.5.2 Sniffing Leak Detection on Refrigerators and Air Conditioners 936
- 19.6 Industrial Tightness Testing of Mass-Production Components 937
 - 19.6.1 Basics 937
 - 19.6.2 Industrial Testing of Series Components 937
 - 19.6.2.1 Envelope Testing Method for Vacuum Components (Method A1 in EN 1779) 938
 - 19.6.2.2 Vacuum Chamber Method for Overpressure Components (Method B6 in EN 1779) 938

19.6.2.3 Testing of Hermetically Sealed Components by Means of Bombing
(Method B5 in EN 1779) 940

19.6.2.4 Testing of Food Packaging in Flexible Test Chambers 941

References 942

Further Reading 942

Appendix 943

Index 1003

Directory of Products and Suppliers 1023

